



# Dual Pressure Sensors

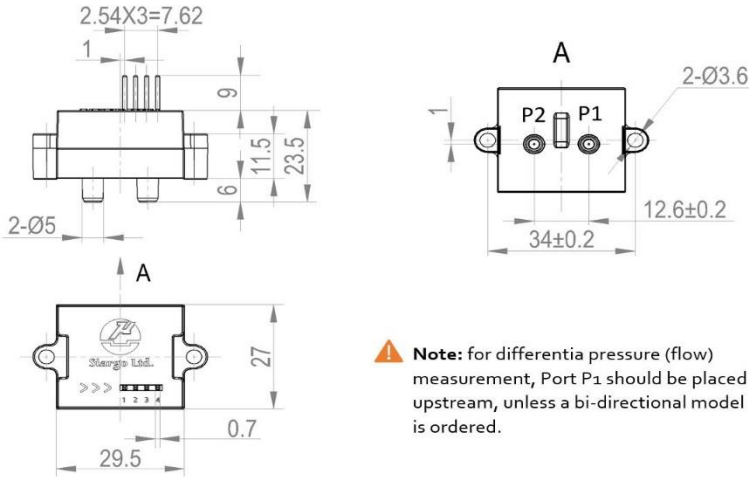
With piezo and thermal sensing

FSP2000 Series

FSP2000 series dual pressure sensors offer the unique combination of a differential and a gauge pressure sensor utilizing the MEMS thermal and piezo sensing technology with smart electronic circuitry. The designed sensing ranges allow that it can be readily applied to medical applications such as a CPAP ventilator for both flow and gauge pressure measurement with a small footprint per the direction of the CPAP development.

FSP2000 measures a differential pressure up to  $\pm 500\text{Pa}$ , and gauge pressure  $\pm 100\text{ cmH}_2\text{O}$ .

## Dimensions



**Note:** for differential pressure (flow) measurement, Port P1 should be placed upstream, unless a bi-directional model is ordered.

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## Specifications

Differential pressure	250 / 500 / $\pm 250$ / $\pm 500$	Pa
Gauge pressure	-5-100 / $\pm 100$	cmH <sub>2</sub> O
Accuracy, differential pressure*	$\pm(2.0+0.5FS)$	%
Accuracy, gauge pressure	$\pm 1.0FS$	%
Response time	1.8	msec
Repeatability	$\pm 0.5$	%
Compensated temperate range	-5 ~ +65	°C
Pressure rating	50	kPa
Altitude correction	Fully compensated	
Warm-up time (max)	10	sec
Humidity	0~100 (no condensation)	%RH
Power supply, voltage	3.0~5.5	Vdc
Power supply, minimal current	10	mA
Pneumatic flow resistance	<95	sccm@500Pa
Output	Linear, I <sup>2</sup> C	
Vibration	20g; MIL-STD-883E, Method 2002.4.	
Storage temperature	-20~75	°C

**Note:** Parameters specified at the calibration conditions.

## Product selection

